



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/361,980
Filing Date: July 28, 1999
Applicant: Yasuaki Tsuzuki et al.
Group Art Unit: 1765
Examiner: Lynette T. Umez-Eronini
Title: Method of Etching Metallic Thin Film On Thin Film Resistor
Attorney Docket: 4041J-000439

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Alexandria, Virginia 22313-1450

AMENDMENT

Sir:

In response to the Office Action mailed June 20, 2003, Paper No. 21, please amend the application as follows and consider the remarks set forth below.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 7 of this paper.